

Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) A method of forming a plurality of films on a base, the method comprising:

forming a first film of ~~the~~ a plurality of films in a first area of the base, the forming of the first film including ~~an~~ a first ejection of a first material from a first nozzle ~~without a solvent dispersing the first material that is~~ and a first ejection of a second material from a second nozzle, the first ejection of the first material and the first ejection of the second material being carried out during a first period; and

forming a second film of the plurality of films ~~that is formed~~ in a second area of the base and that is separated from the first film, the forming of the second film including ~~an~~ a second ejection of the first material from the first nozzle ~~that is~~ and a second ejection of the second material from the second nozzle, the second ejection of the first material and the second ejection of the second material being carried out during a second period,

the first film being formed when the first ejection of the first material ~~from the first nozzle~~ and the first ejection of the second material during the first period ~~is~~ are completed,

the base being provided in a first chamber during the first period,

the second film being formed when the second ejection of the first material ~~from the first nozzle~~ and the second ejection of the second material during the second period ~~is completed,~~ are completed, and

the base being provided in the first chamber during the second period.

2. (Previously Presented) The method according to Claim 1,

the base being provided in an atmosphere that is adjusted to a pressure of 10^{-3} torr or less during at least a part of the first period.

3. (Previously Presented) The method according to Claim 1,
the base being provided in an atmosphere that is adjusted to a pressure of 10^{-5} torr or less during at least a part of the first period.

4. (Currently Amended) The method according to Claim 1, further comprising:
detecting ~~an~~ a failure of the first ejection failure of the first material, the
detecting including a third ejection of the first material from the first nozzle. nozzle to a third
area on the base.

5. (Currently Amended) The method according to Claim 4,
the detecting of ~~the ejection~~ detects the failure of the first ~~nozzle including an~~
ejection of the first ~~material from the first nozzle to a third area on the base.~~ material.

6. (Currently Amended) The method according to Claim 52,
the inspection of the preliminary film being performed by a measurement of
light-reflectivity of the preliminary film.

7. (Previously Presented) The method according to Claim 52,
the inspection of the preliminary film being performed by a measurement of
light-transmissivity of the preliminary film.

8. (Currently Amended) The method according to Claim 1, further comprising:
forming a third film of the plurality of films ~~that is formed on~~ the first film, the
forming of the third film including ~~an~~ a first ejection of a ~~second~~ third material that is carried
out during a third period.

9. (Currently Amended) The method according to Claim 1,
the first material being ejected in a ~~form gas~~ gaseous form from the first nozzle
to the first chamber during the first period.

10. (Currently Amended) The method according to Claim 9,
the first material being ejected in the ~~form gas~~ gaseous form from the first nozzle to the first chamber during the second period.
11. (Currently Amended) The method according to Claim 53,
the second material being ejected in a ~~form gas~~ gaseous form from the ~~second~~ third nozzle to the first chamber during a third period in which the first ejection of the ~~second~~ third material from the ~~second~~ third nozzle is carried out.
12. (Canceled)
13. (Previously Presented) The method according to Claim 8, further comprising:
forming a fourth film of the plurality of films ~~that is formed on the second~~ film, the forming of the fourth film including ~~an~~ a second ejection of the ~~second~~ third material that is carried out during a fourth period.
14. (Currently Amended) ~~A~~ The method of forming a plurality of films on a base,
~~the method comprising: according to claim 1,~~
forming a first film of the plurality of films ~~in a first area of the base, the~~
~~forming of the first film including an ejection of a first material from a first nozzle without a~~
~~solvent dispersing the first material that is carried out during a first period; and~~
forming a second film of the plurality of films ~~in a second area of the base, the~~
~~second film being separated from the first film, the forming of the second film including an~~
~~ejection of the first material from the first nozzle that is carried out during a second period,~~
the first film being formed when the ejection of the first material during the
first period is carried out,
the base being provided in a first chamber during the first period,
the second film being formed when the ejection of the first material during the
second period is completed, and

~~the base being provided in the first chamber during the second period each of~~
the first film and the second film including the first material and the second material.

15. (Currently Amended) A method of manufacturing an electronic device, the method comprising:

forming at least a part of ~~the~~an electronic device by using the method according to Claim 1.

16. (Previously Presented) The method according to Claim 15,
the first material being used for at least one of a conductive film, a semiconductor film, and an insulating film.

17. (Currently Amended) The method according to Claim ~~15~~,14, further comprising:

providing a pattern prior to ~~the ejecting of the first material from the first nozzle during the first period is carried out,~~

~~the plurality of films being formed according to the pattern.~~forming of the first film.

18. (Currently Amended) A method of manufacturing an electro-optical device, the method comprising:

forming at least a part of ~~the~~an electro-optical device by using the method according to Claim 1.

19. (Currently Amended) A method of manufacturing an electro-optical device, the method ~~comprising using the method of claim 1 to form:~~comprising:

at least a part of ~~the electro-optical device;~~ and

~~at least one of an electron-transporting layer, a hole-transporting layer, a light emitting layer, and an electrode included in an electro-optical element included in the electro-optical device.~~the method according to claim 1,

the plurality of films being included in an electro-optical device.

20. (Currently Amended) The method according to Claim 19, further comprising:
forming partitions that surround ~~at least one each~~ of the ~~light-emitting layer,~~
~~the electron-transporting layer and the hole-transporting layer.~~plurality of films.

21-30. (Canceled)

31. (Currently Amended) The method according to Claim 4,
the detecting of the ~~ejection failure being carried out using a sensor of the first~~
ejection of the first material being carried out using a sensor.

32. (Previously Presented) The method according to Claim 1, further comprising:
sensing at least one film of the plurality of films.

33. (Previously Presented) The method according to Claim 32,
the sensing of the at least one film including an irradiation of the at least one
film with a light source.

34. (Previously Presented) The method according to Claim 32,
the sensor measuring at least one of a transmission light that transmits the at
least one film and a reflection light that is reflected by the at least one film.

35. (Currently Amended) The method according to Claim 1,
the first ejection of the first material from the first nozzle and the first ejection
of the second material from the second nozzle during the first period is carried out at a first
position of the first nozzle relative to the base, and

the second ejection of the first material from the first nozzle and the second
ejection of the second material from the second nozzle during the second period is carried out
at a second position of the first nozzle and the second nozzle relative to the base.

36. (Currently Amended) The method according to Claim 35,
further comprising:

moving a position of the first nozzle and the second nozzle relative to the base from the first position ~~to~~to the second position.

37. (Currently Amended) The method according to Claim 1,
the first nozzle and the second nozzle being ~~one nozzle of~~among a plurality of nozzles provided in a discharge head.

38. (Previously Presented) The method according to Claim 1, further comprising:
sensing the first film by a sensor.

39. (Previously Presented) The method according to Claim 1, further comprising:
detecting a positional deviation between a first location on the base where the first film is actually formed and a second location on the base where the first film is to be formed.

40. (Currently Amended) The method according to Claim 18,
the electro-optical device including an organic electroluminescent element,
and
the first film being one of ~~an electron-transporting layer, a hole-transporting layer, a light-emitting layer and an electrode~~ the plurality of films included in the organic electroluminescent element.

41. (Currently Amended) The method according to Claim 1,
the first nozzle and the second nozzle being ~~one of~~among a plurality of nozzles,

a third material being ejected from a third nozzle of the plurality of nozzles during at least part of the first period, and

the first film including the first ~~material~~material, the second material and the third material.

42. (Currently Amended) The method according to Claim 1, further comprising:

performing a scanning movement of a head including the first ~~nozzle~~. nozzle
and the second nozzle.

43. (Previously Presented) The method according to Claim 42,
the scanning movement of the head being performed during at least a part of a
fifth period between the forming of the first film and the forming of the second film.

44. (Currently Amended) The method according to Claim 42,
the first nozzle and the second nozzle being ~~one nozzle of~~ among a plurality of
nozzles provided in the head.

45. (Currently Amended) The method according to Claim 44,
~~the discharge head~~ a nozzle being constructed to adjust a posture of the
~~discharge head~~ nozzle by a θ direction adjusting mechanism, a Z direction adjusting
mechanism, and a Y adjusting mechanism.

46. (Previously Presented) The method according to Claim 45,
each of the θ direction adjusting mechanism, the Z direction adjusting
mechanism, and the Y adjusting mechanism being operated.

47. (Canceled)

48. (Currently Amended) The method according to Claim 1, further comprising:
setting a first relative position of the first nozzle and the second nozzle to the
base before the forming of the first film is carried out; and

setting a second relative position of the first nozzle and the second nozzle
relative to the base before the forming of the second film is carried out.

49. (Currently Amended) The method according to Claim 1, further comprising:
setting a first relative position of the first nozzle and the second nozzle relative
to the base before the first ejection of the first material from the first nozzle and the second

ejection of the second material from the second nozzle during the first period is carried out;
and

setting a second relative position of the first ~~nozzle, nozzle and the second~~
nozzle relative to the base before the third ejection of the first material from the first nozzle
and the fourth ejection of the second material from the second nozzle during the second
period is carried out.

50. (Currently Amended) A method of manufacturing an electro-optical device,
the method comprising:

forming at least a part of ~~the~~an electro-optical device by the method according
to Claim 41,

each of the first film and the second film being at least a part of the electro-
optical device.

51. (Currently Amended) A method of manufacturing an electro-optical device,
the method comprising:

forming at least part of ~~the~~an electro-optical device by the method according
to Claim 55,

each of the first film and the second film being at least a part of the electro-
optical device.

52. (Currently Amended) The method according to Claim 5,
a preliminary film being formed by the fifth ejection of the first material from
the first nozzle to the third area provided on the base, and

the ~~ejection~~ failure of the first ejection being detected based on an inspection of
the preliminary film.

53. (Currently Amended) The method according to Claim 1, further comprising:

forming a third film of the plurality of films that is formed in a third area provided on the base different from the first area and that is separated from the first film, the forming of the third film including ~~an~~ a first ejection of a ~~second-third~~ material from a ~~second-third~~ nozzle different from the first ~~nozzle~~ nozzle and the second nozzle.

54. (Currently Amended) The method according to Claim 1, further comprising:

forming a third film of the plurality of films that is formed ~~on~~ in a third area of the base different from the first area, the forming of the third film including ~~an~~ a first ejection of a ~~second-third~~ material from a ~~second-third~~ nozzle different from the first nozzle and the second nozzle that is carried out during the first period.

55. (Previously Presented) The method according to Claim 1,

a third material being ejected from the first nozzle during at least a part of the first period, and

the first film including the first material and the third material.

56. (Currently Amended) The method according to Claim 50,

an organic electroluminescent element being include in the electro-optical device, and

the first film being one of ~~an electron-transporting layer, a hole-transporting layer, a light-emitting layer and an electrode include~~ the plurality of films included in the organic electroluminescent element.

57. (Currently Amended) The method according to Claim 51,

an organic electroluminescent element being ~~include~~ included in the electro-optical device, and

the first film being one of ~~an electron-transporting layer, a hole-transporting layer, a light-emitting layer and a an electrode include~~ the plurality of films included in the organic electroluminescent element.

58. (Currently Amended) The method according to claim 4,
the ~~detection of~~ detecting the ~~ejection-failure~~ of the first ejection of the first
material is performed by spectroscopic means.